

Claims

What is claimed is:

1. A memory device comprising;
an array of memory formations associated with a lithographic feature of a wafer surface, each memory formation comprising;
a first electrode formed from a bit line of the wafer;
two second electrodes positioned sideways of the first electrode; and
a selectively conductive media placed between the first electrode and each one of the second electrodes, the first electrode operable with each of the second electrodes to selectively activate a memory portion of the selective conductive media.
2. The memory device of claim 1, each second electrode being substantially vertical and stacked laterally next to a side of the first electrode.
3. The memory device of claim 1, the selectively conductive media comprises at least one of a passive material and an organic material.
4. The memory device of claim 3, the organic material is a polymer.
5. The memory device of claim 3, the first electrode is operative with the second electrode as to activate a memory portion of the organic material.
6. The memory device of claim 1, the selectively conductive material is being formed by a depositing system.
7. The memory device of claim 1, the first electrode formed according to a single or dual damascene process.

8. A method for fabricating a memory cell comprising:
 - providing a wafer having a bit line electrode with a raised surface above a substrate layer;
 - forming a selectively conductive layer over the raised surface and the substrate layer;
 - forming a top electrode layer over the selectively conductive layer; and
 - etching a surface to form a lithographic feature with a wall comprising a formed memory cell thereupon, the formed memory cell having the bit line electrode associating with two adjacent memory elements, each memory element including portions of the selective conductive layer and the top electrode layer.
9. The method according to claim 8, associating with two adjacent memory elements further comprises selectively activating a portion of the memory element.
10. The method according to claim 8, etching a surface further comprises etching a surface of the top electrode layer or a surface of the selectively conductive layer.
11. The method according to claim 8, etching a surface further comprises etching a surface of the bit line electrode.
12. The method according to claim 8, further comprising;
etching a surface of the selective conductive layer before forming the top electrode layer.
13. The method according to claim 8, etching a surface of the selective conductive layer further comprises a CMP process.
14. The method according to claim 8, further comprising;
forming a barrier layer to mitigate diffusion of the first electrode and the top electrode into a layer.
15. The method according to claim 8, further comprising;
forming the selectively conductive layer by a chemical vapor deposition process.

16. The method according to claim 8 further comprising;
forming at least one word line to access one or more of the memory cells fabricated in accordance with claim 8.
17. The method according to claim 8, further comprising forming a Cu₂S layer.
18. The method according to claim 8 further comprising forming the selective conductive layer and the top electrode layer by gas phase reaction process.
19. The method according to claim 8 further comprising forming a partitioning component next to the top electrode layer.
20. A system for fabricating an organic memory device comprising;
means for forming a memory cell on a sidewall of a lithographic feature; and
means for partitioning the memory cell from a further memory cell.